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Attorney Docket No. 1082.1042

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of:

Hitoshi YAMADA, et al.

Application No.: 10/076,333

Group Art Unit: 2875

Confirmation No.: 2004

Filed: February 19, 2002

Examiner: Dalei Dong

For: GAS DISCHARGE TUBE AND METHOD FOR FORMING ELECTRON EMISSION  
LAYER IN GAS DISCHARGE TUBE

**RESPONSE TO RESTRICTION REQUIREMENT**

Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

Sir:

In response to the Office Action mailed January 16, 2004, applicants elect Claims 4-21  
of Group II, with traverse.

Respectfully submitted,

STAAS & HALSEY LLP

Date:

January 26, 2004

By:

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